Special Session 분과 [TE2-SS] Beyond 7-nm Technology

	파티클 오염으로 인한 극자외선 노광 기술용 펠리클의 열적 내구성 평가
TE2-SS-1	Yong Ju Jang ¹ , Seong Ju Wi ² , Ha Neul Kim ² , and Jinho Ahn ^{1,2,3}
10:45~11:00	¹ Division of Nanoscale Semiconductor Engineering, Hanyang University, ² Division of
	Materials Science and Engineering, Hanyang University, ³ Institute of Nano Science and
	Technology, Hanyang University Wefer Seels Conformal and Law Temperature Synthesis of Layered Tin
	Wafer-Scale, Conformal, and Low-Temperature Synthesis of Layered Tin Disulfides for Emerging Non-Planar and Flexible Electronics
	Jung Joon Pyeon ^{1,2} , In-Hwan Baek ^{1,3} , Woo Chul Lee ^{1,3} , Hansol Lee ⁴ , Sung Ok Won ⁴ ,
	Ga-Yeon Lee ⁵ , Taek-Mo Chung ⁵ , Jeong Hwan Han ⁶ , Chong-Yun Kang ^{1,2} , and Seong
TE2-SS-2	Keun Kim ¹
11:00~11:15	¹ Center for Electronic Materials, KIST, ² KU-KIST Graduate School of Converging
	Science and Technology, Korea University, ³ Department of Materials Science and
	Engineering and Inter-University Semiconductor Research Center, Seoul National
	University, ⁴ Advanced Analysis Center, KIST, ⁵ Division of Advanced Materials, KRICT,
	⁶ Department of Materials Science and Engineering, SEOULTECH
TE2-SS-3 11:15~11:30	Machine-Learning-Based Device Optimization with TCAD Bokyeom Kim and Mincheol Shin School of Electrical Engineering, KAIST
	The Effect of Post Annealing for Atomic Layer Deposited P-type SnO Semiconductor
TE2-SS-4 11:30~11:45	Su-hwan Choi ¹ , Jung-hoon Lee ² , Hyun-jun Jeong ² , Seok-goo Jeong ¹ , and Jin-seong Park ^{1,2}
	¹ Division of Nanoscale of Semiconductor Engineering, Hanyang University, ² Divison of Materials Science and Engineering, Hanyang University
	Sub-µA and 3-bit per Cell Operation of Self-rectifying Resistive Memory in a 1 Mb Crossbar Array Device
TE2-SS-5	Kanghyeok Jeon ^{1,2} , Jin Joo Ryu ¹ , Doo Seok Jeong ² , Min Kyu Yang ³ , and Gun Hwan
11:45~12:00	Kim ¹
	¹ Division of Advanced Materials, KRICT, ² Division of Materials Science and Engineering,
	Hanyang University, ³ Department of Computer Car Mechatronics, Sahmyook University
TE2-SS-6 12:00~12:15	Improved Measurement Accuracy with TSOM Image Registration at Sub-Pixel Level Junhee Jeong, Youngmin Park, and Joonghwee Cho Department of Embedded Systems Engineering, Incheon National University
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